

Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No. 30205/39511	Serial No. To be Assigned
		Applicant Seong Hwan Park	
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INFORMATION DISCLOSURE STATEMENT

U.S. PATENT DOCUMENTS							
*Examiner Initials	Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate	

FOREIGN PATENT DOCUMENTS								
*Examiner Initials	Document Number	Publication Date	Country	Class	Subclass	Translation		
						Yes	No	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)	
TN	Fujimura et al., "Ashing of the Ion Implanted Resist Layer," Digest of Papers 1989 2 nd MicroProcess Conference, July 2-5, 1989.

EXAMINER	<i>[Signature]</i>	DATE CONSIDERED	2/3/05
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance <u>and</u> not considered. Include copy of this form with next communication to applicant.			